

METHOD AND DEVICE FOR CORRECTING IMAGING ERRORS
OF AN OPTICAL SYSTEM, AND A USE OF THE DEVICE

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ABSTRACT

A method and a device for determining imaging errors of an optical system in the production of a mask for semiconductor component fabrication, including detecting at least one parameter for the characterization of the mask, selecting a stored correction data record from a correction database in a manner dependent on at least one parameter for the characterization of the mask, then determining optical measurable properties of the mask using a measuring system, combining the measurement results of the optical properties with the correction data record associated with the mask in a data processing device, and subsequently storing a measurement data record with the corrected measurement result in a database system. The measurement data record is then used for the correction of imaging errors.